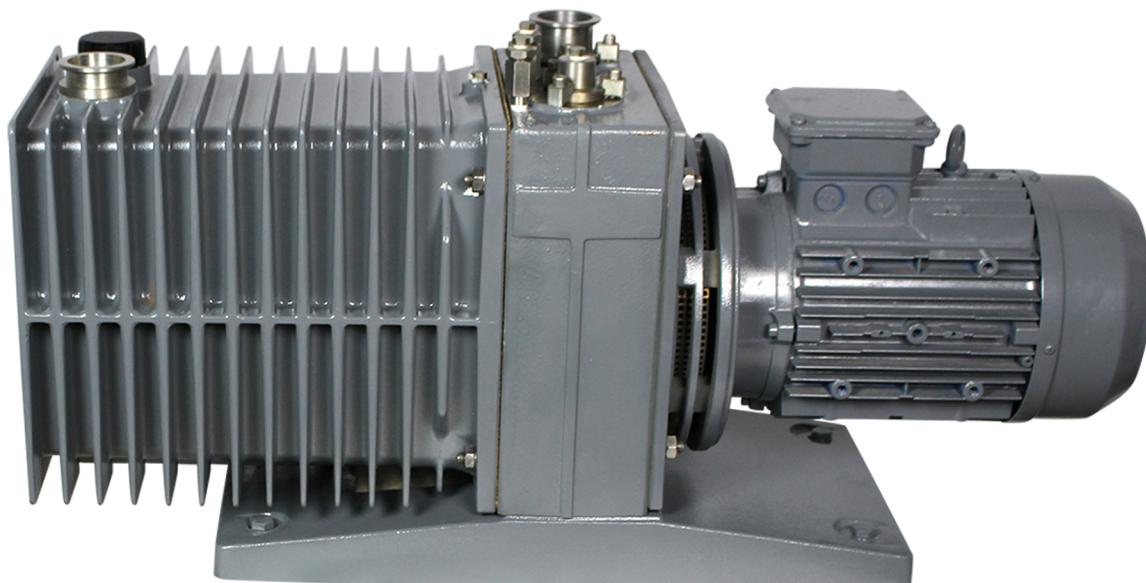




# Alcatel 2010C2, 2015C2, 2021C2, 2033C2, 2063C2 Technical Specifications

	Units	2010C2	2015C2	2021C2	2033C2	2063C2
Nominal pumping speed (*)	50Hz	m <sup>3</sup> /h	9.7	15	20.7	30
	60Hz	cfm	6.8	10.6	14.6	23.3
Pneurop pumping speed (*)	50Hz	m <sup>3</sup> /h	8.5	12.5	16.5	27
	60Hz	cfm	6	8.8	11.8	18.8
Ultimate partial pressure (*)	mbar	5.10 <sup>-4</sup>				
Ultimate total pressure (*) closed gas ballast	mbar	3.10 <sup>-3</sup>				
Weight (max)	kg (lbs)	26 (57.2)	27 (59.4)	28 (61.6)	76 (167)	98 (216)
Dimensions	see page	22	22	22	24	24
Electrical motors	see page	68	68	68	90	90
Max nominal power rating	50/60Hz	kW	0.45/0.55	0.45/0.55	0.45/0.55	1.1/1.3
Min ambient temperature	°C (°F)	12 (54)	12 (54)	12 (54)	12 (54)	12 (54)
Max ambient temperature	°C (°F)	45 (113)	45 (113)	45 (113)	45 (113)	45 (113)
Oil capacity	l	0.95	0.95	0.98	3.6	7
Inlet flange	ISO-KF	DN 25	DN 25	DN 25	DN 40	DN 40
Exhaust flange	ISO-KF	DN 25	DN 25	DN 25	DN 40	DN 40

(\*) : according to Pneurop specifications; with ALCATEL 113 synthetic fluid.



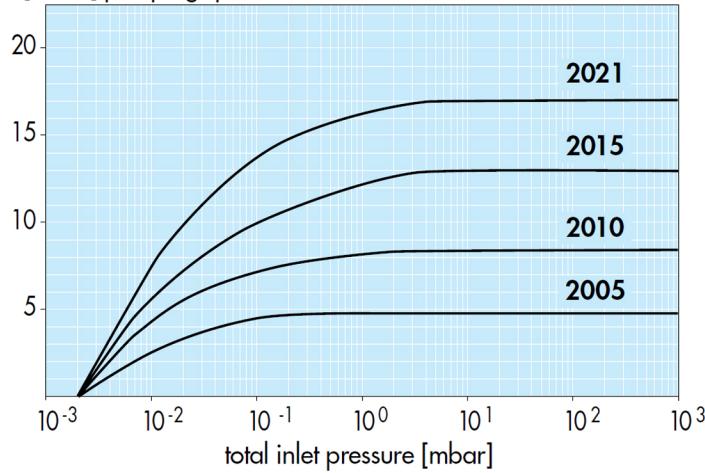


# Alcatel 2010C2, 2015C2, 2021C2, 2033C2, 2063C2 Pumping Curves

**50Hz**

2005I/C1 - 2010I/C1/C2  
2015I/C1/C2 - 2021I/C1/C2

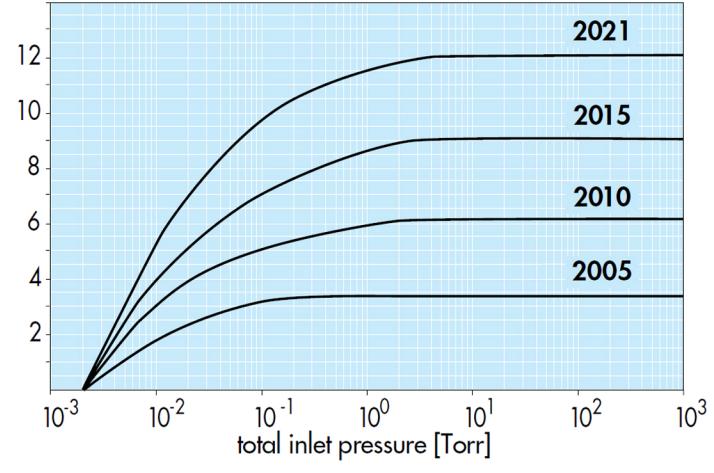
[m<sup>3</sup>/h] pumping speed



**60Hz**

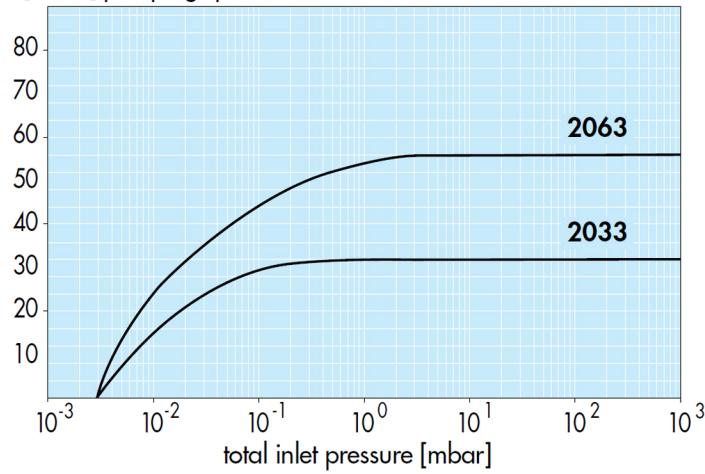
2005I/C1 - 2010I/C1/C2  
2015I/C1/C2 - 2021I/C1/C2

[cfm] pumping speed



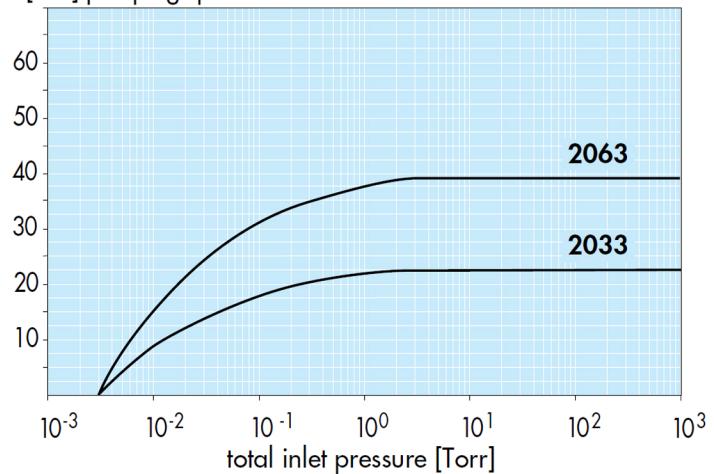
2033SD/C1/C2/H1  
2063SD/C1/C2/H1

[m<sup>3</sup>/h] pumping speed



2033SD/C1/C2/H1  
2063SD/C1/C2/H1

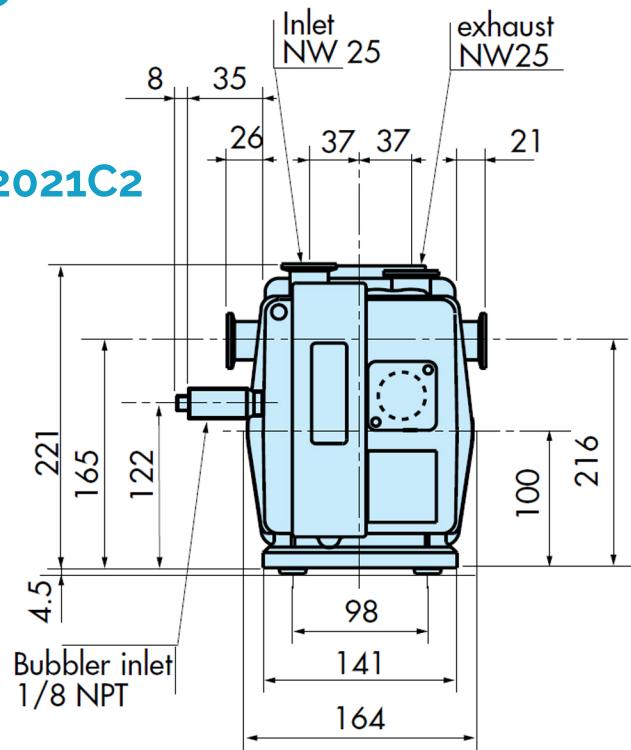
[cfm] pumping speed



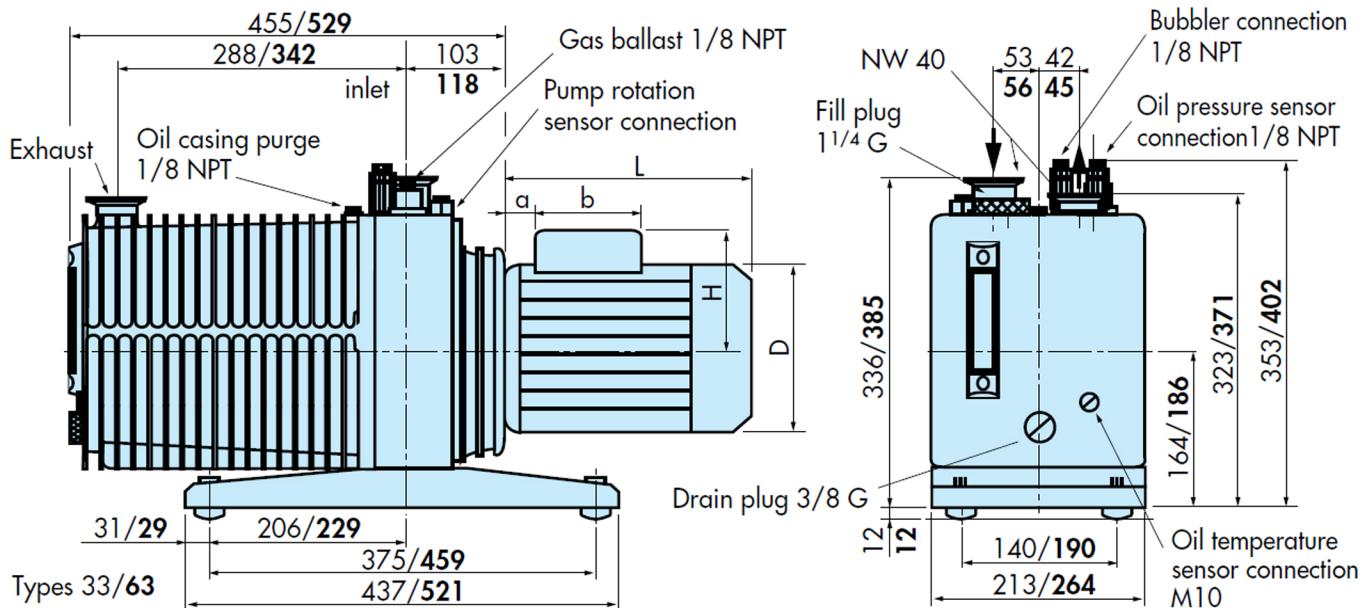


# Alcatel 2010C2, 2015C2, 2021C2, 2033C2, 2063C2 Dimensions

2010C2, 2015C2, 2021C2



2033C2, 2063C2





## **Alcatel 2010C2, 2015C2, 2021C2, 2033C2, 2063C2**

### **Features & Benefits**

- designed for most corrosive applications
- reliable operation in aggressive conditions
- made of stainless steel, gray cast iron & aluminum
- chromium oxide coating on bearing surfaces
- anti-suckback provides vacuum integrity
- high strength oil sight glass
- free of sensitive materials
- efficient gas ballast
- forced lubrication
- bubbler purge



### **Applications**

- plasma/dry etching • reactive sputtering • ion implantation • PECVD
- freeze drying • CVD • LPCVD • load lock • oxygen pumping